IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Thomas McWaid et al.		
Title:	System For Sensing A Sample		
Application No.:	10/729,609	Filing Date:	December 5, 2003
Examiner:	Not yet assigned	Group Art Unit:	2856
Docket No.:	TNCR.169US2	Conf. No.:	2888

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application. Copies of the documents listed on the accompanying Form PTO-1449 were previously submitted in Application No. 09/313,962, filed May 18, 1999, now U.S. Patent No. 6,520,505, Application No. 08/730,641, now U.S. Patent No. 5,948,972, issued September 7, 1999, and Application No. 08/362,818, filed December 22, 1994, now U.S. Patent No. 5,705,741, issued January 6, 1998, from which this Application claims an earlier effective filing date.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(c). A check including $180.00 for the information disclosure statement fee under 37 C.F.R. § 1.17(p), is enclosed. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope address to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on October 5, 2004.

Franklin Dyer

Respectfully submitted,

James S. Hsue
Reg. No. 29,545

10/5/04
Date

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U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	1	2,691,887	Oct., 1954	Rinker.			
	2	2,728,222	Dec., 1955	Becker et al.			
	3	3,283,568	Nov., 1966	Reason.			
	4	4,103,542	Aug., 1978	Wheeler et al.			
	5	4,391,044	Jul., 1983	Wheeler.			
	6	4,441,177	Apr., 1984	Groh et al.			
	7	4,574,625	Mar., 1986	Olasz et al.			
	8	4,641,773	Feb., 1987	Morino et al.			
	9	4,669,300	Jun., 1987	Hall et al.			
	10	4,724,318	Feb., 1988	Binnig.			
	11	4,883,959	Nov., 1989	Hosoki et al.			
	12	4,902,892	Feb. 1990	Okayama et al.			
	13	5,146,690	Sep., 1992	Breitmeier.			
	14	RE33387	Oct. 1990	Binnig			
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	25	5,414,690	May., 1995	Shido et al.			
	26	5,415,027	May 1995	Elings et al.			

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	27	5,426,302	Jun., 1995	Marchman et al.			
	28	5,481,521	Jan., 1996	Washizawa et al.			
	29	5,488,862	Feb., 1996	Neukermans et al.			
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	31	5,509,300	Apr., 1996	Chamberlin et al.			
	32	5,513,168	Apr., 1996	Fujihara et al.			
	33	5,614,712	Mar. 1997	Ray			
	34	5,627,365	May., 1997	Chiba et al.			
	35	5,629,790	May., 1997	Neukermans et al.			
	36	5,705,741	Jan. 1998	Eaton et al.			
	37	5,866,806	Feb. 1999	Samsavar et al.			
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							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	39	0361932	Sep., 1989	EP.				
	40	0536827	Sep., 1992	EP.				
	41	0594362	Oct., 1993	EP.				
	42	0633450	Jun., 1994	EP.				
	43	2249910	Oct., 1990	JP				
	44	2009409	Jun., 1979	GB				
	45	WO 88/04047	Jun., 1988	WO.				
	46	WO 94/08204	Apr., 1994	WO				
	47	WO 94/25888	Nov., 1994	WO.				
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		OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)
	49	"A New Force Sensor Incorporating Force-Feedback Control for Interfacial Force Microscopy", S. Joyce et al., Rev. Sci. Instrum., vol. 62, No. 03, Mar. 1991, pp. 710-715.
	50	"From Molecules to Cells: Imaging Soft Samples with the Atomic Force Microscope", M. Radmacher et al., Science, vol. 257, Sep. 25, 1992, pp. 1900-1905.
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	52	"Silicon Wafer Thermal Processing: 300 mm Issues," H. Huff et al., Future Fab International, 1996, pp. 35-49.
	53	"Atomic force microscopy for high speed imaging using cantilevers with an integrated actuator and sensor," S.R. Manalis et al., Appl. Phys. Lett., 68(6), Feb. 5, 1996, pp. 871-873.
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	56	"A Stand-Alone Scanning Force and Friction Microscope," M. Hipp et al., Ultramicroscopy, 42-44(1992), Elsevier Science Publishers B.V., pp. 1498-1503.
	57	"New Scanning Device for Scanning Tunneling Microscope Applications," R. Koops et al., Review of Scientific Instruments,vol. 63, No. 8, Aug. 1992, pp. 4008-4009.
	58	"Scanning Tunneling Microscopy," G. Binnig et al., Helvetica Physica Acts, vol. 55, 1982, pp. 726-735.
	59	"Two-Scanning Tunneling Microscope Devices for Large Samples," G.B. Picotto et al., Review of Scientific Instruments, vol. 64, No. 9, Sep. 1993, pp. 2699-2701.
	60	"A High Precision Micropositioner Based on Magnetostriction Principle," W. Wang et al., Review of Scientific Instruments, vol. 63, No. 1, Jan. 1992, pp. 249-254.
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	63	"Long Range Constant Force Profiling for Measurement of Engineering Surfaces," L.P. Howard, Review of Scientific Instruments, vol. 63, No. 10, Oct. 1992, pp. 4289-4295.
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	65	"Evaluating the Sensitivity of a Fiber-Optic Displacement Sensor," W.C. Oliver, Nano Instruments, Inc., Technotes, no date available.
	66	"To Measure a Molecule," F. Flam, pp. 21-24, no date available.
	67	"The National Institute of Standards and Technology Molecular Measuring Machine: A Long-Range Scanning Tuneling Microscope for Dimensional Metrology," E.C. Teague, Microbeam Analysis, 1989, pp. 545-547.
	68	"Products for Micropositioning," Product Information Brochure published by Physik Instrumente (PI) GmbH & Co., no date available.
	69	"Fiber Optic Proximity Sensors," Product Information Brochure published by Phone-Or, Ltd., Fiber Optic Sensors of Ashkelon ISRAEL, no date available.
	70	"Series 88 Fiber-Optic Displaceent Sensors," G. J.Philps, Sensors, Feb. 1995.
	71	"Nanometrology," E.C. Teague; Proceedings of Scanned Probe Microscopy; STM and Beyond, an Engineering Foundation Conference, Santa Barbara, CA Jan. 1991.
	72	"Microlever with combined integrated sensor/actuator functions for scanning force microscopy," J. Brugger et al., Sensors and Actuators A, 43, 1994, pp. 339-345.
	73	"Rocking-beam force-balance approach to atomic force microscopy," D.A. Grigg et al., Ultramicroscopy, 42-44, 1992, pp. 1504-1508.
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	75	"Thermal Imaging of Electronic Materials and Devices Using the Atomic Force Microscope," A. Majumdar et al., Proceedings of the SPIE--The International Society for Optical Engineering, 1993, Abstract Only.
	76	"Micromachined AFM transducer with differential capacitive read-out," J. Bay et al., J. Micromech. Microeng., vol. 5, 1995, pp. 161-165.
	77	"Dimensional metrology with scanning probe microscopes," J. Griffith et al., J. Appl. Phys., vol. 74, No. 9, Nov. 1, 1993, pp. R83-R109.
	78	"A rocking beam electrostatic balance for the measurement of small forces," G. L. Miller et al., Rev. Sci. Instrum., vol. 62, No. 3, Mar. 1991, pp. 705-709.
	79	"Resonant silicon sensors," G. Stemme, J. Micromech. Microeng., vol. 1, 1991, pp. 113-125.
	80	Written Opinion dated March 29, 2001
	81	International Search Report dated August 30, 2000

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